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(72) Inventors:  
• **VAN ES, Maarten Hubertus**  
**2595 DA 's-Gravenhage (NL)**  
• **SADEGHIAN MARNANI, Hamed**  
**2595 DA 's-Gravenhage (NL)**

(74) Representative: **V.O.**  
**P.O. Box 87930**  
**Carnegieplein 5**  
**2508 DH Den Haag (NL)**

(71) Applicant: **Nederlandse Organisatie voor toegepast-natuurwetenschappelijk onderzoek TNO**  
**2595 DA 's-Gravenhage (NL)**

(54) **ATOMIC FORCE MICROSCOPY CANTILEVER, SYSTEM AND METHOD**

(57) The surface of the atomic force microscopy (AFM) cantilever is defined by a main cantilever body and an island. The island is partly separated from the main body by a separating space between facing edges of the main body and the island. At least one bridge connects the island to the main body, along a line around which the island is able to rotate through torsion of the

at least one bridge. The island has a probe tip located on the island at a position offset from said line and a reflection area. In an AFM a light source directs light to the reflection area and a light spot position detector detects a displacement of a light spot formed from light reflected by the reflection area, for measuring an effect of forces exerted on the probe tip.

